

**IN THE SPECIFICATION***Attorney docket SAT 201**Paragraph at page 16, line 1:*

The work detector 4 detects wafers 14 on a tray 30 approaching a predetermined attraction position (P0 on the Y-axis) and notifies the controller 25. That is, the detector 4 first detects the wafers 14 on the tray 30 (before they reach the predetermined attraction position P0) at a detection position. The detection position is ahead of the predetermined attraction position P0. The controller 25 controls the air cylinder 3-1 of the moving unit 3 (FIG. 5) to lower the Bernoulli arm 2 together with the Bernoulli plates 1 and has the Bernoulli plates 1 arrive at a position whose Z coordinate is at H1 at the time when the wafers 14 arrive at their predetermined position (P0 on the Y-axis). At this time, the controller 25 introduces nitrogen gas from the gas introducing portions 11 and starts attracting the wafers 14, and simultaneously drives the work pushing-up portion 21 to push up the wafers 14 on the center in an attraction direction (the Z axial direction) to separate the wafers 14 from the tray 30. The Bernoulli plates 1 are indicated by s2 in FIG. 7d.

**AMENDMENT**

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